

Exam of Physical and Chemical Analyses of Materials

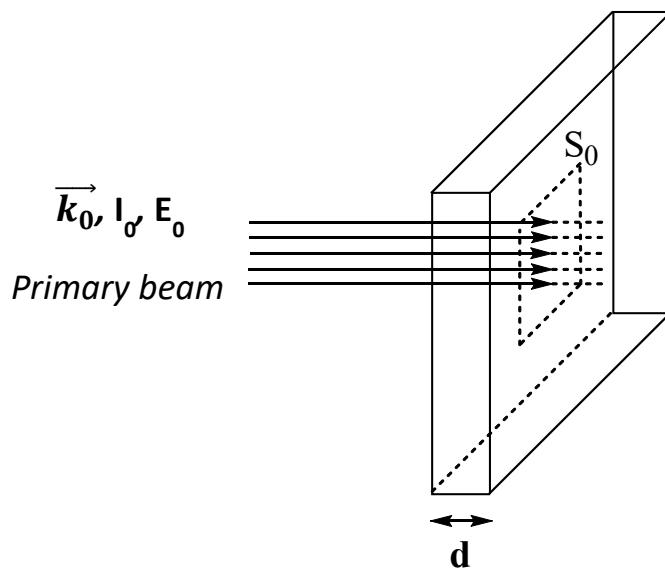
June 2024

Duration: 3 hours

I. Interaction beam-matter

I.1. Interaction beam-matter: matter excitation

During a physical or a chemical analysis of a material, one has to take into account the interaction of a beam with the matter across a surface S_0 . The primary beam is characterized by a wave vector \vec{k}_0 , a beam energy E_0 and a beam intensity I_0 . After interacting with the matter, the primary beam is affected by the different events.



Complete the table by ticking the box(es) which correspond(s) to the parameter(s) mainly affected by the following events:

	\vec{k}_0	$\ \vec{k}_0\ $	E_0	I_0
Absorption				X
Elastic scattering	X			X
Inelastic scattering	X	X	X	X

Complete the following table related to the use of electrons and X-Rays as primary beams:

Event	Nature of the primary beam	Type of scattering	Target
Rayleigh	<i>X-Rays</i>	<i>Elastic</i>	<i>Whole electronic cloud</i>
Compton	<i>X-Rays</i>	<i>Inelastic</i>	<i>electrons</i>
Bremsstrahlung	<i>Electrons</i>	<i>Inelastic</i>	<i>nuclei</i>
Diffraction	<i>X-Rays or Electrons</i>	<i>Elastic</i>	<i>Whole electronic cloud (nuclei location)</i>
Ionisation	<i>X-Rays or Electrons</i>	<i>Inelastic</i>	<i>electrons</i>

Indicate if the following statements are true or false:

	true	false
▪ The modulus of the wave vector is not linked to the energy of its associated particle.	<input type="checkbox"/>	<input checked="" type="checkbox"/>
▪ The cross-section for the Compton effect increases with the energy of the X-Ray photons.	<input checked="" type="checkbox"/>	<input type="checkbox"/>
▪ The Bremsstrahlung generates specific X-Rays.	<input type="checkbox"/>	<input checked="" type="checkbox"/>
▪ Diffraction occurs when the wavelength of the incoming beam and the diffracting object have almost the same size.	<input checked="" type="checkbox"/>	<input type="checkbox"/>
▪ The ionisation of a target atom always takes place at the K level.	<input type="checkbox"/>	<input checked="" type="checkbox"/>

I.2. Interaction beam-matter: matter emission

Complete the following table while considering inelastic scatterings leading to the ionisation of the matter. Indicate if the emission is directly caused by the primary beam (direct emission) or consecutive to the matter relaxation (indirect emission) by ticking the correct(s) box(es).

Primary beam	Emission type	Direct emission	Indirect emission
X-Rays	<i>Photo-electrons</i>	X	
	<i>X-Rays</i>		X
	<i>Auger electrons</i>		X
Electrons	<i>Secondary electrons</i>	X	
	<i>X-Rays</i>		X
	<i>Auger electrons</i>		X

In material analysis, the emission types listed above are used for either microscopic or analytical purposes.

Among the emission types listed above, highlight the one(s) which possesses/possess an energy related to the energy of the primary beam.

Photo-electrons

Among the emitted beams listed above, highlight the one(s) which possesses/possess an energy only related to the chemical nature of the emitting element.

X-Rays and Auger electrons

Among the emitted beams listed above, highlight the one(s) for which it is not clearly possible to correlate its energy to neither the energy of the primary beam nor the chemical nature of the emitting element.

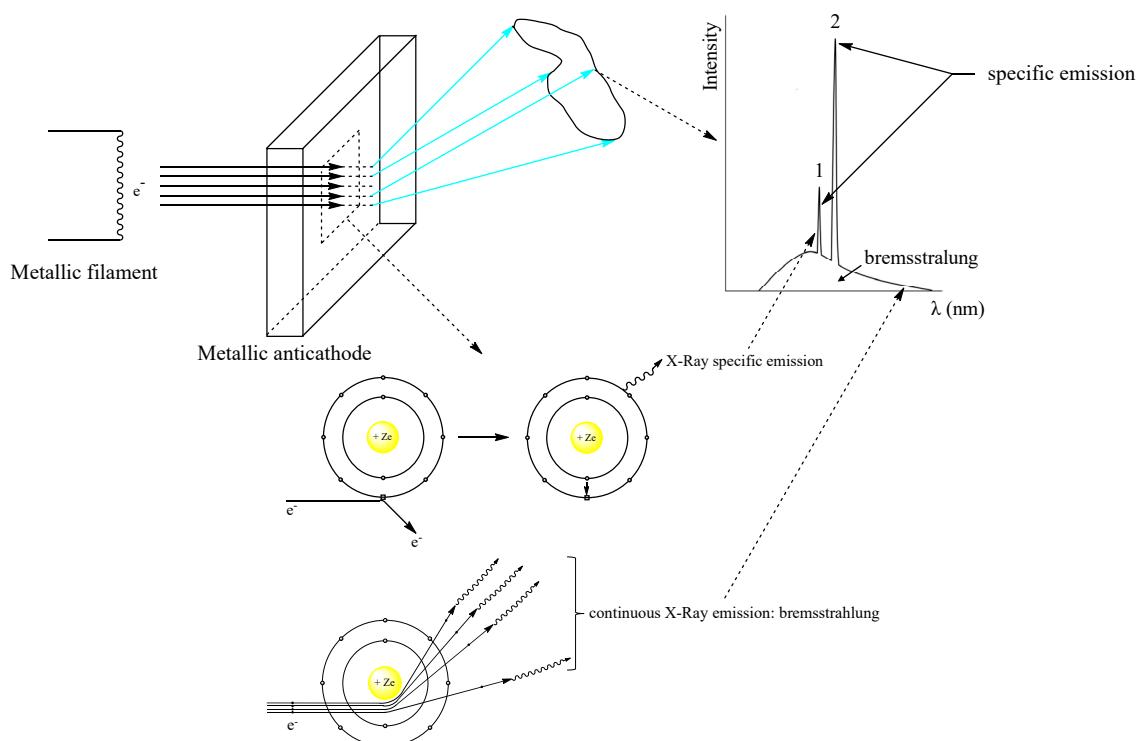
Secondary electrons

Indicate if the following statements are true or false:

	true	false
▪ The probability of X-Ray emission is greater for light chemical elements than for heavy ones.	<input type="checkbox"/>	<input checked="" type="checkbox"/>
▪ The emission of X-Rays follows strict selection rules.	<input checked="" type="checkbox"/>	<input type="checkbox"/>
▪ Auger electrons can be produced by either an X-ray or an electron primary beam.	<input checked="" type="checkbox"/>	<input type="checkbox"/>
▪ The kinetic energy of Auger electrons is correlated to the energy of the primary beam.	<input type="checkbox"/>	<input checked="" type="checkbox"/>
▪ The emission of Auger electrons follows strict selection rules.	<input type="checkbox"/>	<input checked="" type="checkbox"/>

I.3. Interaction beam-matter: X-rays production

XRF and XPS instruments share the same primary beam, that is X-Ray photons. Using a drawing, describe how X-Rays are produced. Indicate on the drawing the mechanism(s) that produces/produce X-rays during the interaction beam-matter using a simple Bohr atom model. Draw the resulting X-ray spectrum: the intensity I of the X-Ray photons as a function of the wavelength λ .



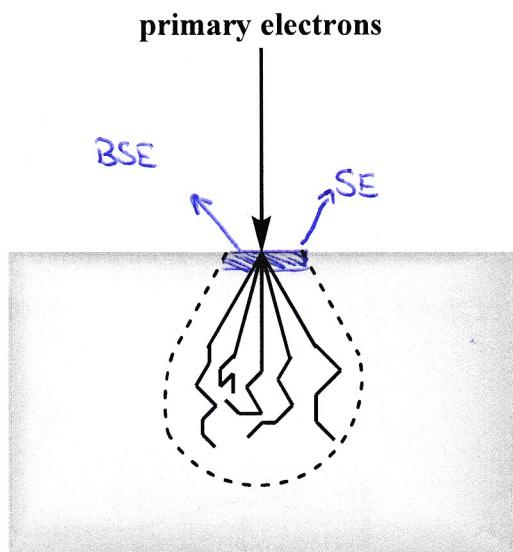
II. Physical characterization of materials

II.1. Electron microscopy

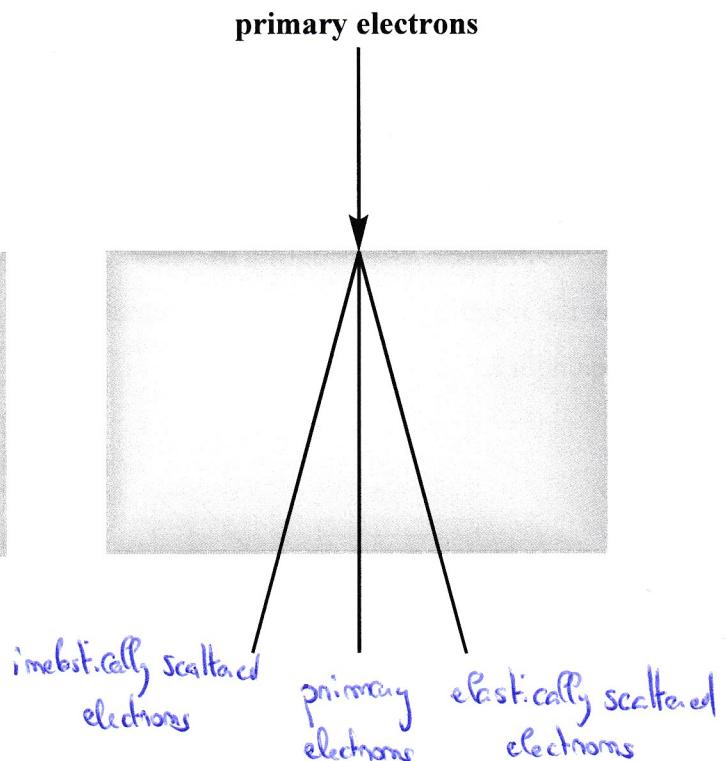
SEM (Scheme A) and TEM (Scheme B) are both related to electron microscopy. Complete the following drawings with:

- the trajectory of the electrons in the studied sample and the specific probed sample volume
- the events recorded for each microscopy and the emission zones of these events

Scheme A: SEM



Scheme B: TEM



Based on the previous question, complete the following table and thick the correct answer(s).

	TEM	SEM
Typical beam energy range	<i>100 to 200 keV</i>	<i>0.1 to 30 keV</i>
Lateral resolution range	<i>Angstöm</i>	<i>Nanometer</i>
Scanning mode	<input type="checkbox"/> yes <input checked="" type="checkbox"/> no	<input checked="" type="checkbox"/> yes <input type="checkbox"/> no
Sample features	<input checked="" type="checkbox"/> size \leq 3 mm <input checked="" type="checkbox"/> thickness $<$ 100 nm <input type="checkbox"/> high surface conductivity <input type="checkbox"/> flat surface <input checked="" type="checkbox"/> specific preparation	<input type="checkbox"/> size \leq 3 mm <input type="checkbox"/> thickness $<$ 100 nm <input checked="" type="checkbox"/> high surface conductivity <input type="checkbox"/> flat surface <input type="checkbox"/> specific preparation
Sample holder	<input type="checkbox"/> conducting holder <input checked="" type="checkbox"/> no requirement	<input checked="" type="checkbox"/> conducting holder <input type="checkbox"/> no requirement
Analysed signals	<i>Transmitted electrons</i>	<i>Secondary electrons</i> <i>Backscattered electrons</i>
Type(s) of image	<i>Diffraction pattern</i> <i>HRTEM</i> <i>BF image</i> <i>DF image</i>	<i>Secondary electrons image</i> <i>Backscattered electrons image</i>

What is the main effect while reducing the energy of the electron primary beam?

Degrading the lateral resolution because the resolution is inversely proportional the wavelength of the primary beam so directly proportional to the primary energy.

In which type of electron microscopy and for which reason(s) it may be sometimes of interest to decrease the energy of the primary electron beam?

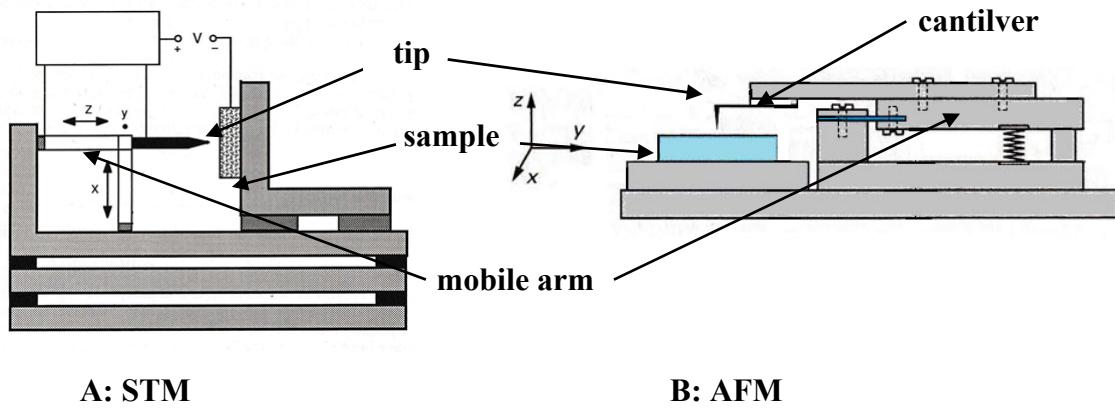
Actually, in SEM when the studied sample is not conducting enough, one can observe the accumulation of electrons at the surface that will causes the blurring of the image and at least the defocusing (loss of image sharpness) and finally the reflection (blinding of the detector) of the primary electron beam. To counteract this problem, a possibility remains into the decrease of the primary electron beam to decrease the accumulation of electrons at the surface of the studied sample. Except the degradation of the lateral resolution and so the sharpness of the image, it will enhance the production of SE and AE so providing more surface details.

Indicate if the following statements are true or false:

	true	false
▪ With TEM, it is possible to obtain morphological information on nanoparticles deposited on an electron transparent material.	<input checked="" type="checkbox"/>	<input type="checkbox"/>
▪ With TEM, it is possible to obtain morphological information on a bulky material.	<input type="checkbox"/>	<input checked="" type="checkbox"/>
▪ With TEM, it is possible to obtain structural information on an amorphous material.	<input type="checkbox"/>	<input checked="" type="checkbox"/>
▪ With TEM, it is possible to obtain topographical information using the method of replicas.	<input checked="" type="checkbox"/>	<input type="checkbox"/>
▪ For SEM studies, the sample must be prepared using the Formvar method.	<input type="checkbox"/>	<input checked="" type="checkbox"/>
▪ In SEM, decreasing the beam energy enhance the production of backscattered electrons.	<input type="checkbox"/>	<input checked="" type="checkbox"/>
▪ In SEM, a sample coating made of gold enhances the production of secondary electrons.	<input checked="" type="checkbox"/>	<input type="checkbox"/>
▪ In SEM, charging effects appear when the electrons at the surface of the material are correctly drained.	<input type="checkbox"/>	<input checked="" type="checkbox"/>

II.2. Scanning probe microscopy

Below are depicted the technical schemes of an AFM and a STM microscopes. Appoint each microscope to the corresponding scheme.



Indicate on the schemes above the location of the sample, the tip, the cantilever and the mobile arm.

Complete the following table by ticking the correct box(es):

	STM	AFM
Tip directly mounted on a mobile arm	X	
Tip indirectly coupled to a mobile arm		X
Tip polarised against the studied material	X	
Setting up a tunnelling current between the tip and the studied sample	X	
Setting up a contact between the tip and the studied sample		X
Sensitive to the forces involved between the tip and the material		X
Sensitive to the electronic states of a material	X	
Analysis of conductors and semiconductors	X	X
Analysis of insulators		X
Lateral resolution at the Angstrom level	X	
Lateral resolution at the nanometre level		X

What is the difference between an STM image obtained from a positive mode (the tip is positively polarised against the sample) and from a negative mode (the tip is negatively polarised against the sample)?

When the tip is positively polarised against the sample, the image corresponds to the iso-density of the electronic states at the energy of the Fermi level EF representing the filled surface states.

When the tip is negatively polarised against the sample, the image will then correspond to the iso-density of the electronic states at an energy higher than the fermi level ($EF + \epsilon$) representing the empty surface states.

Which scanning probe microscopy would you choose to study a biological membrane?

Actually, based on the fact that a biological membrane is an insulating material, I would turn to AFM which is fully dedicated to the study of every kind of material whereas STM, because of the establishment of tunnelling current requires some conducting properties from the studied sample.

With which mode are you going to operate? Base your answer on a brief description of the chosen mode while pointing out its highlights regarding the nature of a biological membrane.

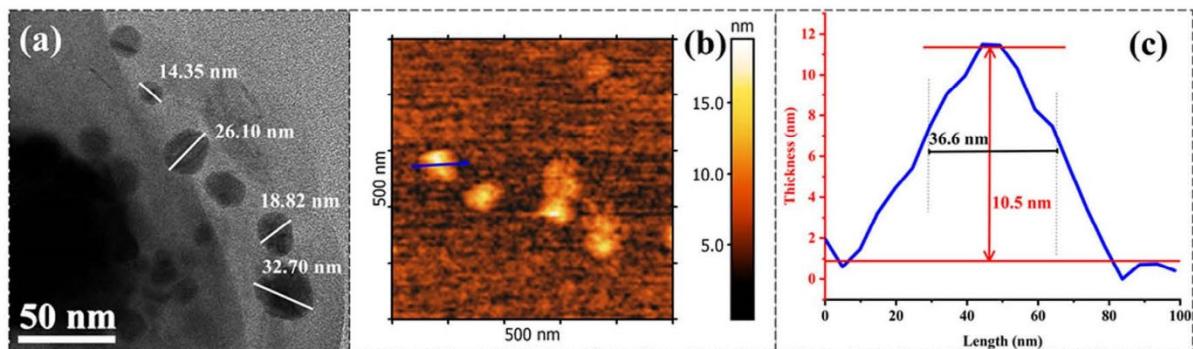
Regarding the running mode, I would rather prefer a taping mode because of the soft nature of the studied sample: Briefly, the tip oscillate at a given amplitude and frequency and the latest is further moved along the surface. The height of the mobile arm is tunned along the z axis to maintain the amplitude of the oscillations leading to a surface profile. The intermittent contact between the tip and the sample in a taping mode is then ideal because it will decrease a lot the influence of the lateral forces that can arise from a contact mode and that will further degrade the sharpness of the image.

Indicate if the following statements are true or false:

	true	false
▪ STM is always performed under vacuum or under inert atmosphere.	<input checked="" type="checkbox"/>	<input type="checkbox"/>
▪ The STM tip is still along the x and y axes.	<input type="checkbox"/>	<input checked="" type="checkbox"/>
▪ STM can be performed at constant height.	<input checked="" type="checkbox"/>	<input type="checkbox"/>
▪ STM can be performed at a constant tip oscillation amplitude.	<input type="checkbox"/>	<input checked="" type="checkbox"/>
▪ AFM is mostly used for morphological studies.	<input type="checkbox"/>	<input checked="" type="checkbox"/>
▪ The AFM tip is moving along the scanned surface.	<input type="checkbox"/>	<input checked="" type="checkbox"/>
▪ AFM performed in contact mode is dedicated to the study of soft surfaces.	<input type="checkbox"/>	<input checked="" type="checkbox"/>
▪ The STM tip can oscillate at a given frequency.	<input type="checkbox"/>	<input checked="" type="checkbox"/>
▪ When AFM is performed in tapping mode, the tip is in intermittent contact with the scanned surface.	<input checked="" type="checkbox"/>	<input type="checkbox"/>

II.3. TEM versus STM

STM and TEM achieve almost the same lateral resolution and then can be compared. Below are displayed the analysis of MgB₂ nanoparticles by TEM and STM:



A) TEM image of the synthetised nanoparticles, **B)** STM image of the synthetised nanoparticles, **C)** resulting topography of a given synthetised nanoparticle.

What kind of TEM image is displayed in figure **A**?

This is a BF image.

The STM image was recorded at a constant tunnelling current of 2 nA. Briefly describe this operating mode.

In a constant tunnelling current approach, the tip of the STM will follow the topography of the scanned sample by adjusting its position along the z axis to conserve the current intensity. The resulting image will represent the distance between the tip and the scanned surface along the x and y axes.

Briefly describe the TEM and STM pictures in terms of morphology and topography.

From a morphological point of view, looking at the TEM picture displays on figure a, one can see a sharp image of the contour of the nanoparticles thus highlighting the morphological character of the TEM analysis. In contrast, when looking at the STM picture of the same nanoparticles, one can observe that the contour of these particle is blurred.

From a topographic point of view, the only manner to access to such information by TEM is to use the replicas (direct or indirect replicas) and to rebuilt an image by means of the series of shots taken from the replicas. In contrast, as said before, STM run in a constant current mode is fully dedicated to grasp the topography of a surface as the image displays the distance between the tip and the surface along the scanning x and y axes.

The topographic profile displayed on figure c relies on which technic: TEM or STM?

According to the previous answers, we can be pretty sure that the topography displayed on figure c was obtained from the STM analysis.

III. Chemical characterization of materials

III.1. General

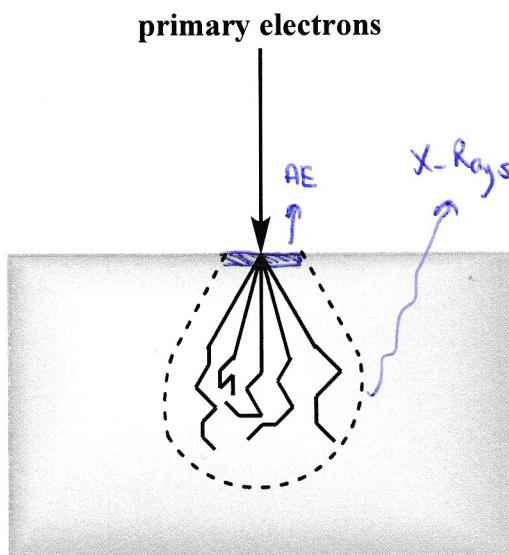
Chemical analysis of a material are mainly carried out using electron or X-ray sources.

Complete the following drawings with:

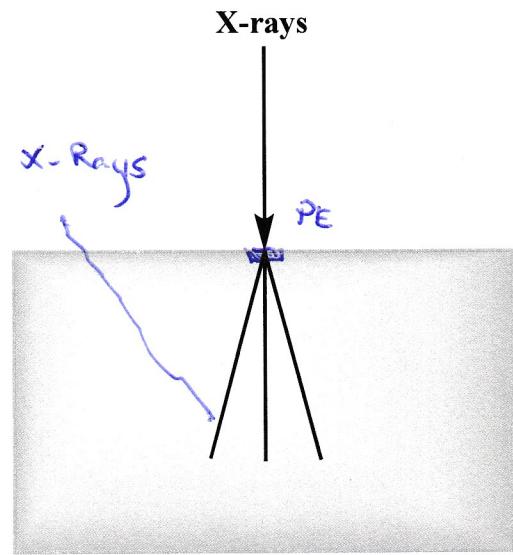
- the trajectory of the primary beam in the studied sample and the specific probed sample volume (in both cases, the primary beam does not emerge from the sample).

- all the events related to analytical purposes and the emission zones of these events.

Scheme A



Scheme B



Indicate if the following statements are true or false:

	true	false
▪ Secondary electrons are considered for chemical analysis.	<input type="checkbox"/>	<input checked="" type="checkbox"/>
▪ Backscattered electrons are considered for chemical analysis.	<input type="checkbox"/>	<input checked="" type="checkbox"/>
▪ Useful electrons in chemical analysis are emitted from the surface of the material.	<input checked="" type="checkbox"/>	<input type="checkbox"/>
▪ For chemical analysis, the brightness of the electron source is of most importance compared to its stability.	<input type="checkbox"/>	<input checked="" type="checkbox"/>
▪ For chemical analysis Hard X-Ray sources are required.	<input type="checkbox"/>	<input checked="" type="checkbox"/>

In analytical chemistry, the proposed analytical method must meet two different features. What are these two features?

The method must be qualitative and quantitative.

III.2. Bulk and surface analyses

Complete the following table by ticking the correct box for each chemical analysis:

	Semi-Bulk	Bulk	Surface
XRFS		X	
XPS			X
XRMA	X		
AES			X

Complete the following table by ticking the correct box for each chemical analysis:

	X-ray as primary beam	Electrons as primary beam
XRFS	X	
XPS	X	
XRMA		X
AES		X

Complete the following table by filling the boxes:

	Background signal	Recorded signal	Side signal(s)
XRFS	<i>Bremsstrahlung</i>	<i>Specific X-Rays</i>	<i>X-Rays from the anticathode</i> <i>X-Rays from Compton effect</i>
XPS	<i>Secondary electrons</i>	<i>Photo-electrons</i> <i>Auger electrons</i>	<i>none</i>
XRMA	<i>Bremsstrahlung</i>	<i>Specific X-Rays</i>	<i>none</i>
AES	<i>Secondary</i>	<i>Auger electrons</i>	<i>Backscattered electrons</i>

XRMA can be achieved thanks to an SEM or using a specific apparatus.

Give the name of this specific apparatus.

Electron Micro-Probe analyser EMPA

What are the differences between the electron sources of these two apparatus?

The two electron sources differ from the fact that the electron gun is different: W for EMPA whereas a LaB6 or a FEG is used in EM. In addition, there is a stabilizing device included in the electron column of the EMPA that stabilizes the intensity of the primary beam. Last, in term of energy, for SEM one can go up to 30 keV whereas for EMPA, one can go up to 50 keV.

Briefly describe the spectrometer associated to each apparatus?

In SEM, the spectrometer is constituted by a single device, the detector which plays the role of analyser and detector. It indeed gives both qualitative and quantitative information.

In EMPA, the spectrometer is constituted by two devices an analyser made of a crystal analyser which select the different emission wavelengths of the elements present in the studied sample and, a detector. Whereas, the provides the qualitative information, the detector gives rise to the quantitative information.

III.3. XRFS vs XPS

XPS and XRFS share the same exciting beam. Nevertheless, the two X-Ray sources are different.

Briefly explain the main spectral differences that exist between these two sources and why it is necessary to have these different spectral features.

In XRFS the X-Ray source must provide the most widespread X-Ray wavelength to ensure the correct excitation of all the chemical elements present in the material, i.e. a polychromatic source. If the same polychromatic source is used in XPS, one element will provide a bunch of photo-electrons of different energies, that will complicate a lot the interpretation of the spectrum. To counteract this problem, one uses a monochromatic source which will ensure the production of only one kind of photo-electrons per analysed chemical element. This will indeed simplify the number of signals present on the XPS spectrum.

Which of these two methods is the most sensitive to the chemical nature of the neighbours of an analysed element?

According to the polychromatic nature of the X-Ray source of XRFS, most of the analysed elements lead to X-Rays resulting from the ionisation of the K level of the target chemical element. These core electrons are almost not influenced by the surrounding neighbours of the target. In contrast, due to the monochromatic nature of the X-Ray source of XPS and because the source is made of a light chemical element, one cannot always ensure the ionisation of the K level of all the chemical elements. Therefore, the target ionisation levels are most of the time the ones close or involved in chemical bounds, the energies of the target electrons being strongly dependent on the neighbourhood.

Which parameter represents the influence of the neighbourhood of an analysed element?

The chemical shift.

On a XPS spectrum, one can observe two different types of signals. How one can distinguish both?

On a XPS spectrum one can observe the signals of Auger and Photo-electrons. To distinguish both, one can change the nature of the anticathode material, so the wavelength of excitation because, the energy of the photo-electrons is linked to the energy of the exciting beam whereas, the energy of the Auger electrons is only related to the chemical nature of the emitting element.

One of these two technics must follow a correction process to achieve a good quantitative accuracy. Which technic is concerned by these so-called matrix effects? For the concerned technic, give the set of correction parameters that one must applied to meet a proper quantitative analysis.

The concerned technic is XRFS which needs a correction according to the nature of the target chemical element to access to an accurate quantitative determination.

The correction that one has to take into account are: the homogeneity of the grain of the considered material across K_G , the absorption of the emitted X-Rays as a function of the matrix K_A and the secondary fluorescence of a target element across K_F . The correction constant is then $K_m = K_G K_A K_F$. The quantitative equation using an internal standard S to obtain the relative atomic concentration of a given chemical element i is:

$$\frac{C_{ra,i}}{C_{ra,S}} = K_m \frac{I_i}{I_S} \Rightarrow C_{ra,i} = C_{ra,S} K_m \frac{I_i}{I_S}$$

TABLEAU PÉRIODIQUE DES ÉLÉMENS

<http://www.periodni.com/fr/>

GROUPE		PERIODE																		3 IIIA				14 IVA			15 VIA			16 VIA			17 VIA			18 VIIA																
1	1 IA	2 IIA		3 IIIA			4 IVB				5 VIB			6 VIB			7 VIB			8 VIB			9 VIB			10 VIB			11 IB			12 IB			13 IIIA			14 IVA			15 VIA			16 VIA			17 VIA			18 VIIA		
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1	1 IA	2	2 IIA	3	3 IIIA	4	4 IVB	5	5 VIB	6	6 VIB	7	7 VIB	8	8 VIB	9	9 VIB	10	10 VIB	11	11 IB	12	12 IB	13	13 IIIA	14	14 IVA	15	15 VIA	16	16 VIA	17	17 VIA	18	18 VIIA																	
1	H	2	Li	3	Na	4	Mg	5	Al	6	Si	7	Ge	8	As	9	Se	10	Br	11	Kr	12	Rn	13	La	14	Pr	15	Tb	16	Yb	17	Lu	18	Uuo																	
1	1.0079	2	9.0122	3	6.941	4	9.0122	5	10.811	6	10.811	7	10.811	8	10.811	9	10.811	10	10.811	11	10.811	12	10.811	13	10.811	14	10.811	15	10.811	16	10.811	17	10.811	18	10.811																	
1	HYDROGÈNE	2	LITHIUM	3	BERYLLOUM	4	CALCIUM	5	SCANDIUM	6	TITANIUM	7	VANADIUM	8	CHROMIUM	9	MANGANESE	10	FER	11	KALIUM	12	BERYLLOUM	13	ALUMINIUM	14	CHALCOGENIUM	15	PHOSPHORE	16	CHLORE	17	FLUOR	18	VIIA																	
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1	1.0079	2	6.941	3	22.990	4	24.305	5	24.305	6	24.305	7	24.305	8	24.305	9	24.305	10	24.305	11	24.305	12	24.305	13	24.305	14	24.305	15	24.305	16	24.305	17	24.305	18	24.305																	
1	1.0079	2	6.941	3	22.990	4	24.305	5	24.305	6	24.305	7	24.305	8	24.305	9	24.305	10	24.305	11	24.305	12	24.305	13	24.305	14	24.305	15	24.305	16	24.305	17	24.305	18	24.305																	
1	1.0079	2	6.941	3	22.990	4	24.305	5	24.305	6	24.305	7	24.305	8	24.305	9	24.305	10	24.305	11	24.305	12	24.305	13	24.305	14	24.305	15	24.305	16	24.305	17	24.305	18	24.305																	
1	1.0079	2	6.941	3	22.990	4	24.305	5	24.305	6	24.305	7	24.305	8	24.305	9	24.305	10	24.305	11	24.305	12	24.305	13	24.305	14	24.305	15	24.305	16	24.305	17	24.305	18	24.305																	
1	1.0079	2	6.941	3	22.990	4	24.305	5	24.305	6	24.305	7	24.305	8	24.305	9	24.305	10	24.305	11	24.305	12	24.305	13	24.305	14	24.305	15	24.305	16	24.305	17	24.305	18	24.305																	
1	1.0079	2	6.941	3	22.990	4	24.305	5	24.305	6	24.305	7	24.305	8	24.305	9	24.305	10	24.305	11	24.305	12	24.305	13	24.305	14	24.305	15	24.305	16	24.305	17	24.305	18	24.305																	
1	1.0079	2	6.941	3	22.990	4	24.305	5	24.305	6	24.305	7	24.305	8	24.305	9	24.305	10	24.305	11	24.305	12	24.305	13	24.305	14	24.305	15	24.305	16	24.305	17	24.305	18	24.305																	
1	1.0079	2	6.941	3	22.990	4	24.305	5	24.305	6	24.305	7	24.305	8	24.305	9	24.305	10	24.305	11	24.305	12	24.305	13	24.305	14	24.305	15	24.305	16	24.305	17	24.305	18	24.305																	
1	1.0079	2	6.941	3	22.990	4	24.305	5	24.305	6	24.305	7	24.305	8	24.305	9	24.305	10	24.305	11	24.305	12	24.305	13	24.305	14	24.305	15	24.305	16	24.305	17	24.305	18	24.305																	
1	1.0079	2	6.941	3	22.990	4	24.305	5	24.305	6	24.305	7	24.305	8	24.305	9	24.305	10	24.305	11	24.305	12	24.305	13	24.305	14	24.305	15	24.305	16	24.305	17	24.305	18	24.305																	
1	1.0079	2	6.941	3	22.990	4	24.305	5	24.305	6	24.305	7	24.305	8	24.305	9	24.305	10	24.305	11	24.305	12	24.305	13	24.305	14	24.305	15	24.305	16	24.305	17	24.305	18	24.305																	
1	1.0079	2	6.941	3	22.990	4	24.305	5	24.305	6	24.305	7	24.305	8	24.305	9	24.305	10	24.305	11	24.305	12	24.305	13	24.305	14	24.305	15	24.305	16	2																					